

# Optical Plasma Diagnostics in High Intensity Electron Beam Diodes

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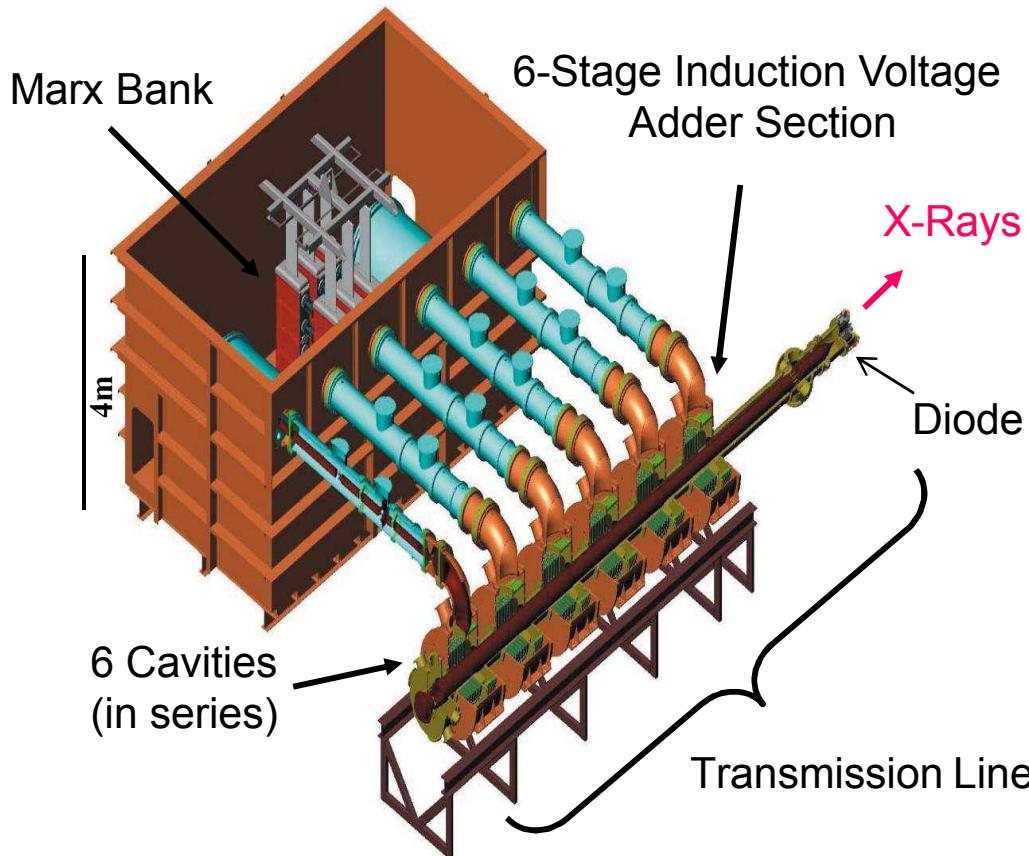
# Outline

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- RITS-6 Accelerator.
- Negative Polarity Rod Pinch (NPRP) Diode.
- Self-Magnetic Pinch (SMP) Diode.
- Optical Diagnostics Layout on RITS.
- PI-Max ICCD Single Frame Fast Imaging System
- Optical Streak Imaging System
- Avalanche Photodiodes
- Plasma Spectroscopy Diagnostic
- Plasma Parameters Inferred from Spectral Analyses
- Electric and Magnetic Field Measurements
- Summary



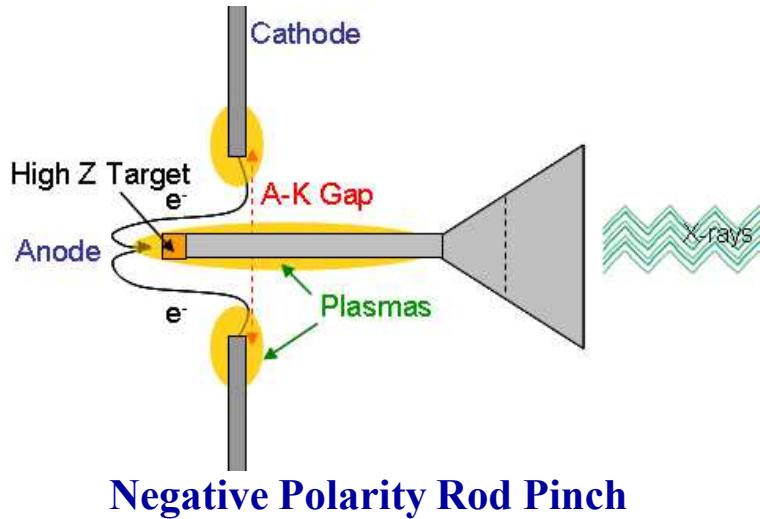
# RITS-6 Accelerator at Sandia National Laboratories



RITS-6 is a multi-MeV Marx driven six-stage Inductive Voltage Adder (IVA) machine, capable of driving a variety of electron beam diodes<sup>1</sup>.

<sup>1</sup>D. Johnson, et al., Proc. 15<sup>th</sup> IEEE Int. Pulsed Power Conf (IEEE, Jun. 13-17, 2005) pp. 314–317.

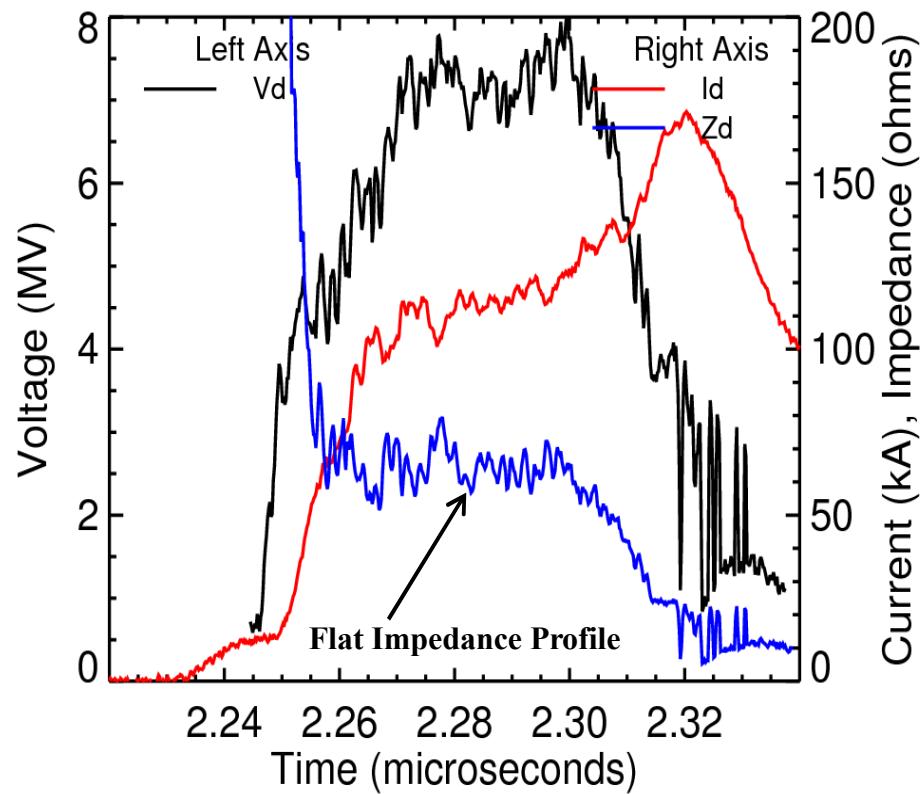
# Negative Polarity Rod Pinch (NPRP) Diode Electrical Characteristics



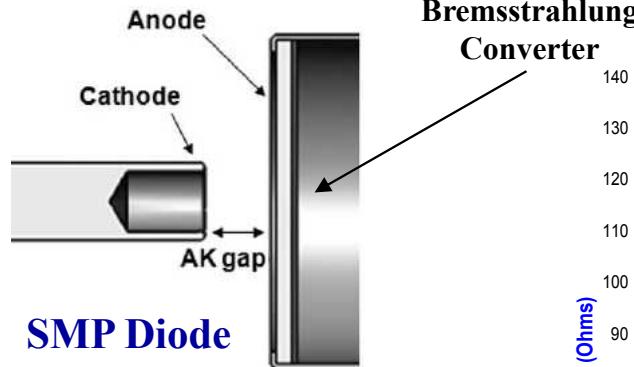
## Negative Polarity Rod Pinch

## NPRP Diode Parameters

- 6-7 MV
- 120 kA
- 70ns Electrical Pulse
- 50ns Radiation Pulse
- > 120 Rads @ 1 meter
- < 2.6 mm spot size

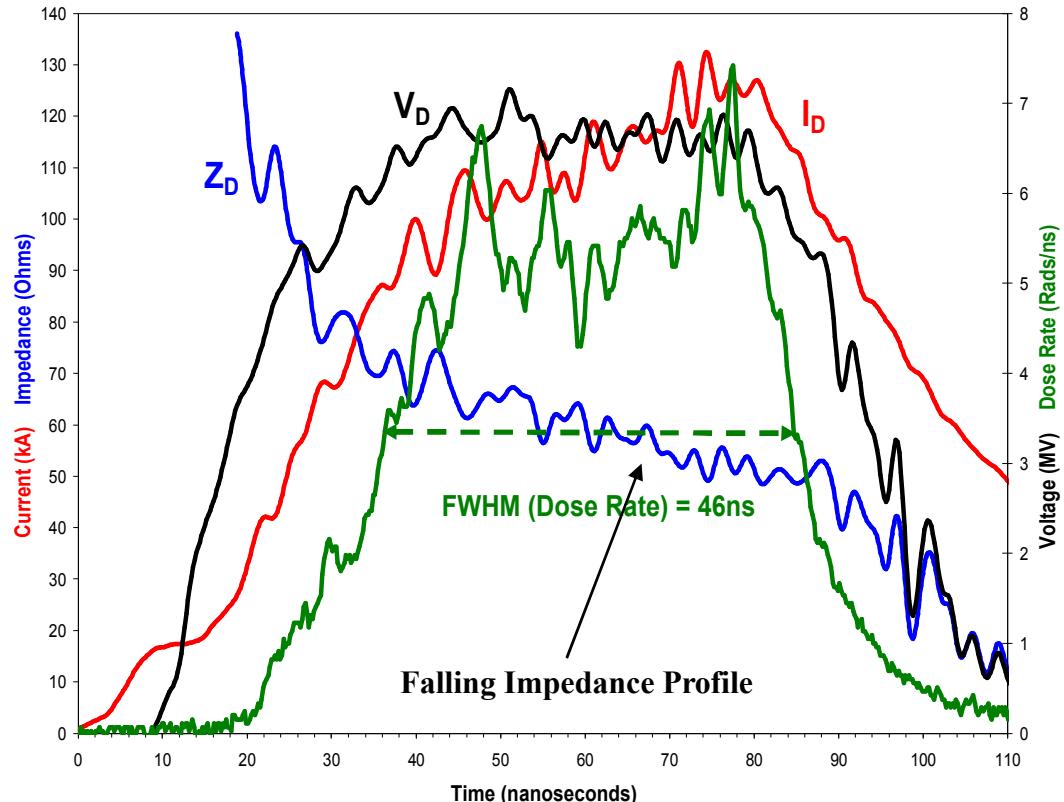


# Self-Magnetic Pinch (SMP) Diode Electrical Characteristics



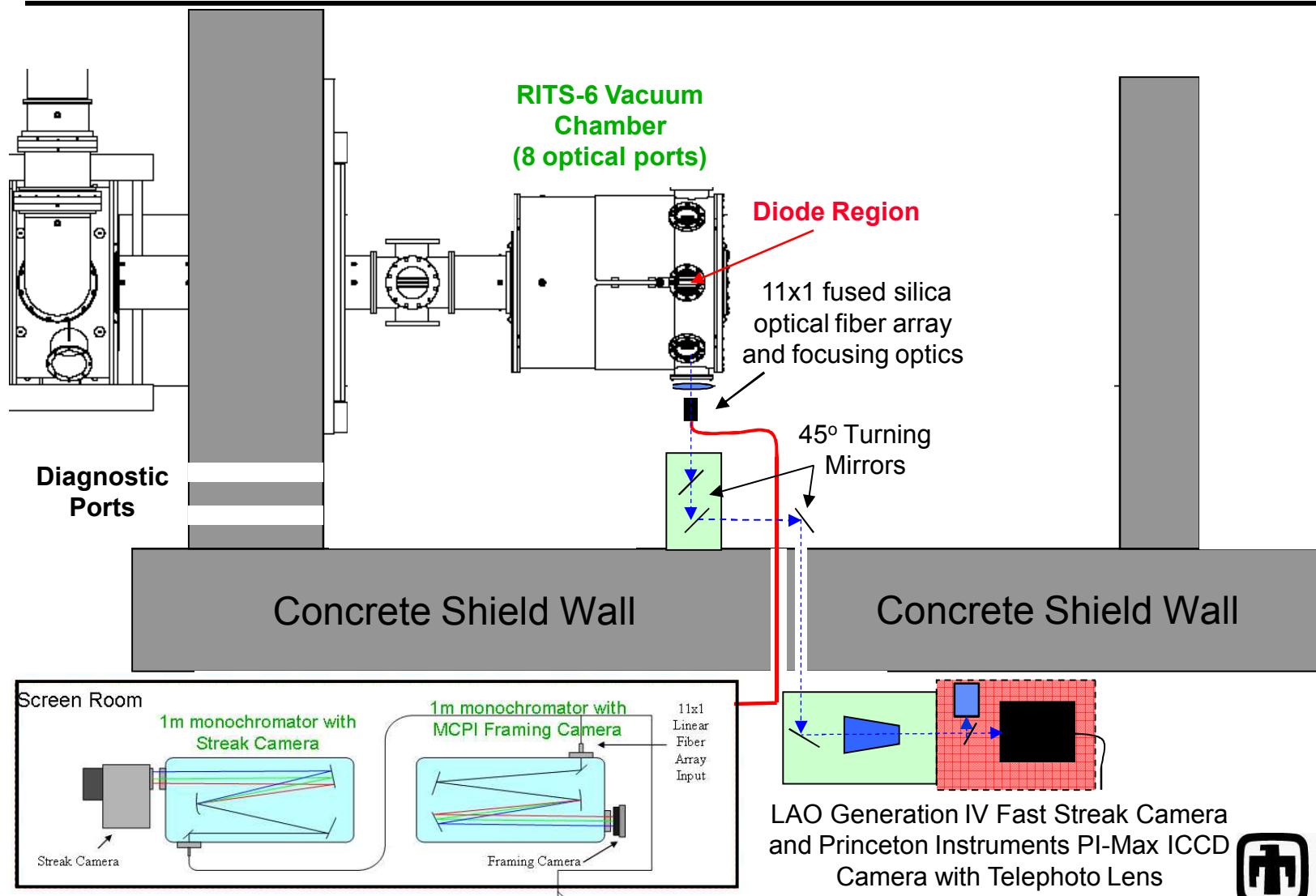
## SMP Diode Parameters

- 4-7.5 MV
- 80-150 kA ( $\sim 15\%$  ions)
- $50 \Omega$  Impedance
- 70ns Electrical Pulse
- 45ns Radiation Pulse
- 90-350 Rads @ 1 meter
- $\leq 2.7$  mm focal spot size



**MA/cm<sup>2</sup> current densities  
at the anode!**

# Optical Diagnostics Layout on the RITS-6 Accelerator



# PI-Max ICCD Single Frame Imaging System

The ICCD Framing camera is a commercially available Princeton Instruments model PI-Max.

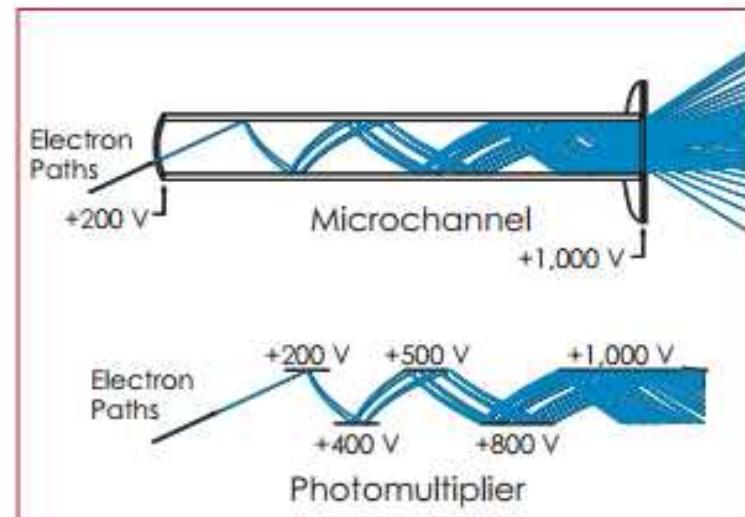
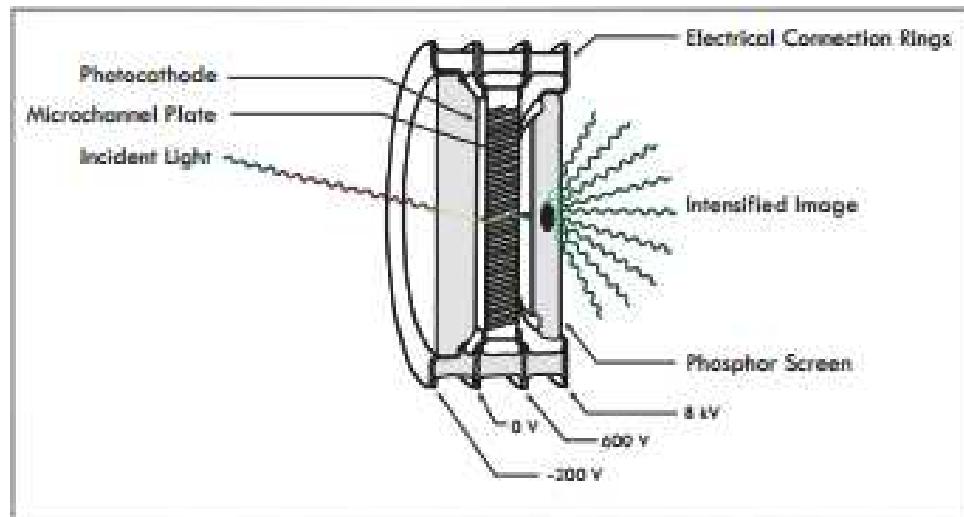
## Princeton Instruments PI-Max ICCD Camera

- Gen III filmless GaAsP photocathode (HBf)
- 25mm fiber-optic bonded 1:1 image intensifier
- P43 phosphor screen
- Front-Illuminated CCD
- 1340x1300 pixel array
- 20 micron pixel size
- < 7ns gating
- > 50% peak QE



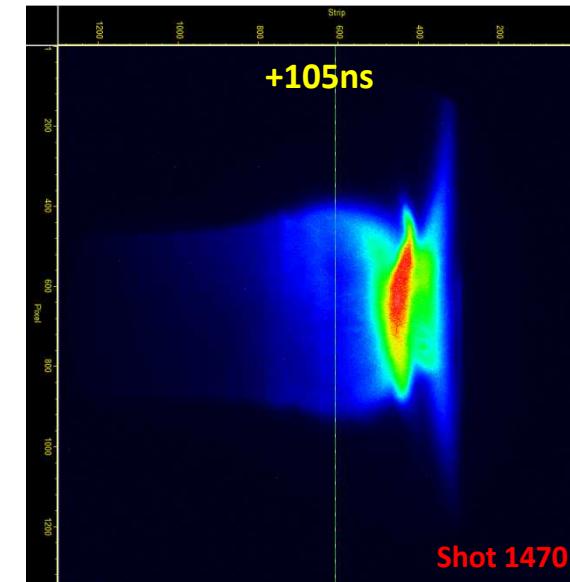
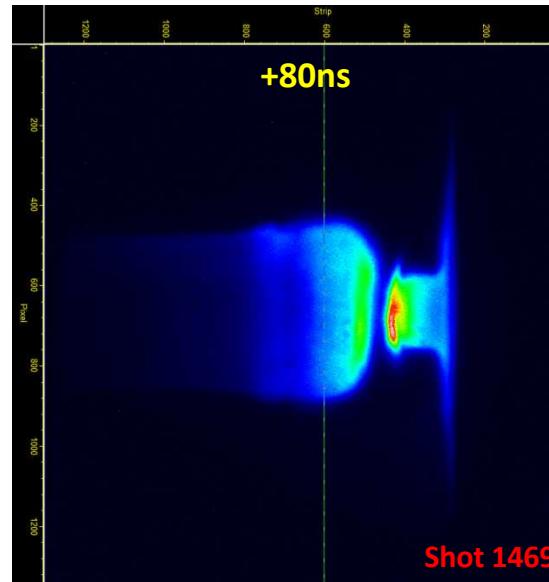
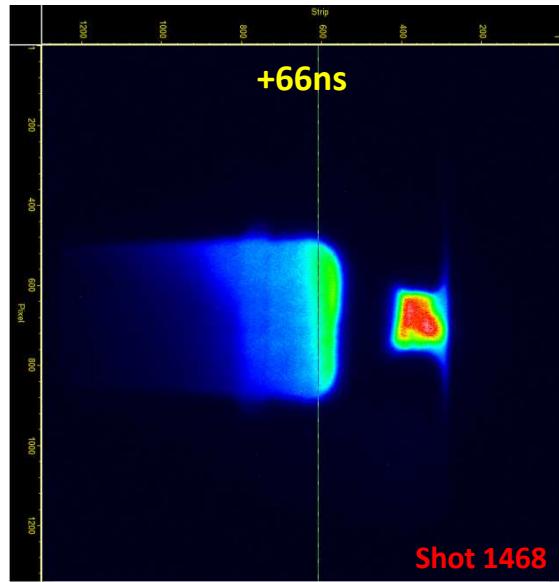
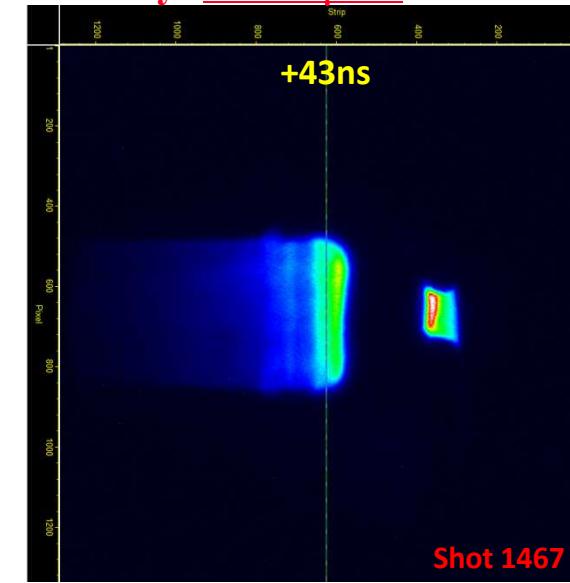
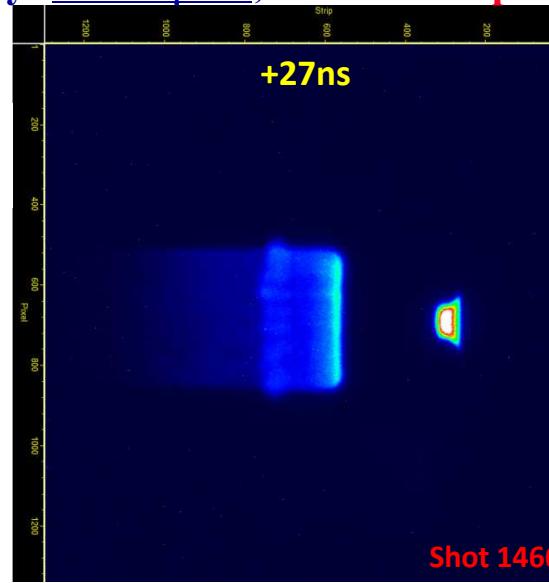
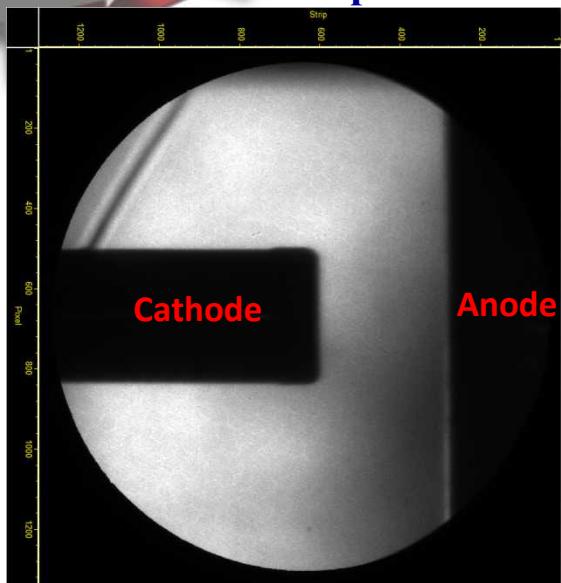
Princeton Instruments  
PI-Max Camera

(A) Microchannel Plate,  
(B) Fiber-optic faceplate, and (C) CCD



# Framing Camera Images of Electrode Plasma Expansion

Anode Expansion Velocity: 3.5cm/μsec; Cathode Expansion Velocity: 1.7cm/μsec



\*Green line represents original cathode position

\*10ns images

# Optical Streak Camera Plasma Imaging Diagnostic

The optical streak imaging system was designed around the NSTec Gen IV Streak Camera.

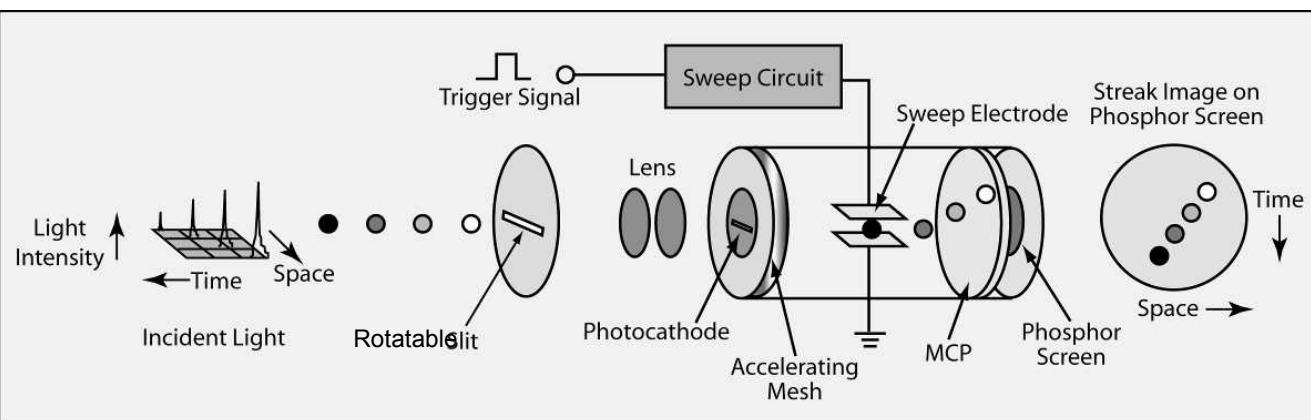
## NSTec Gen IV Streak Camera

- Continuously Selectable Sweep Rates from 20ns to 500 $\mu$ s
- Photonis P510 Streak Tube
- 6 $\mu$ m Fiber Faceplate (Input/Output)
- 35mm x 4mm Active Area Multi-alkali S-20 Photocathode
- 60mm Aluminized P-22 Phosphor Screen
- Selectable/rotatable input slit sizes
- Full remote control capability from external work station



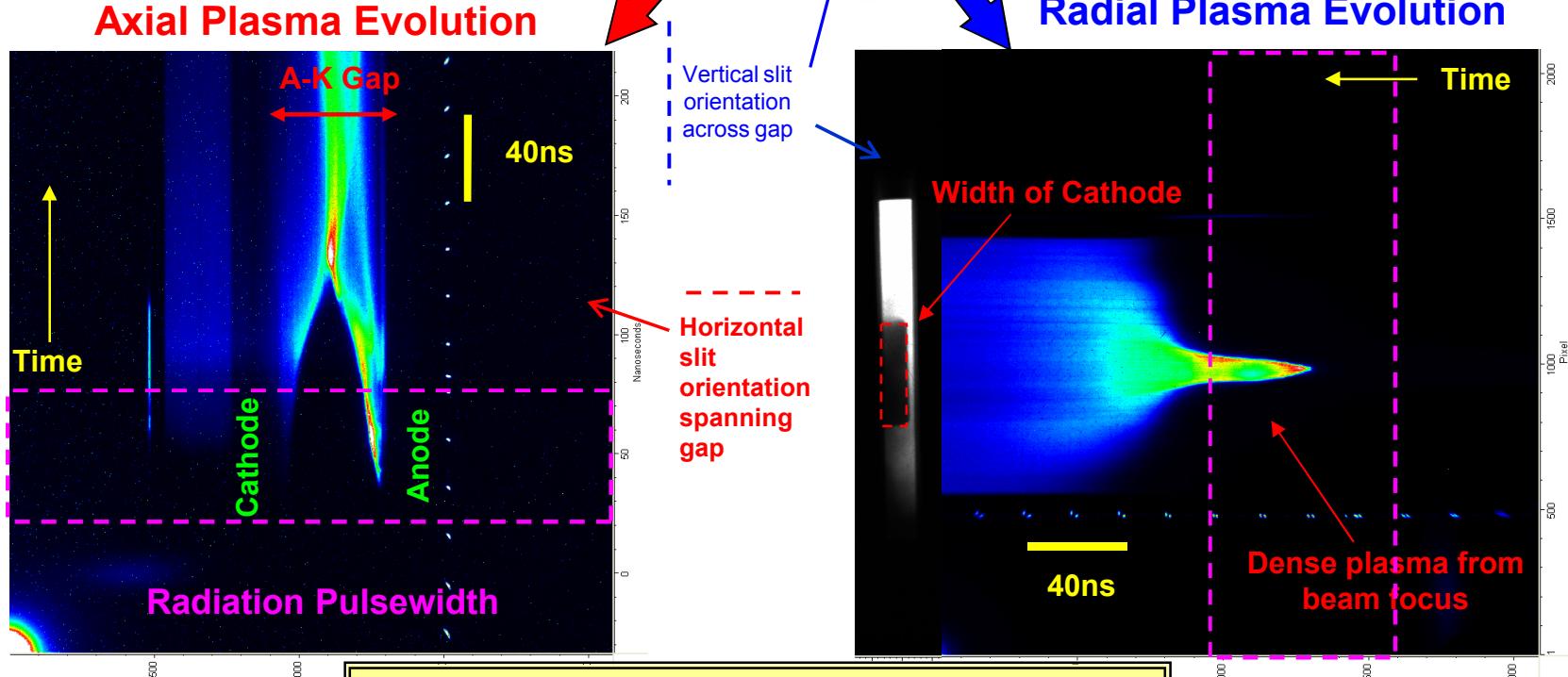
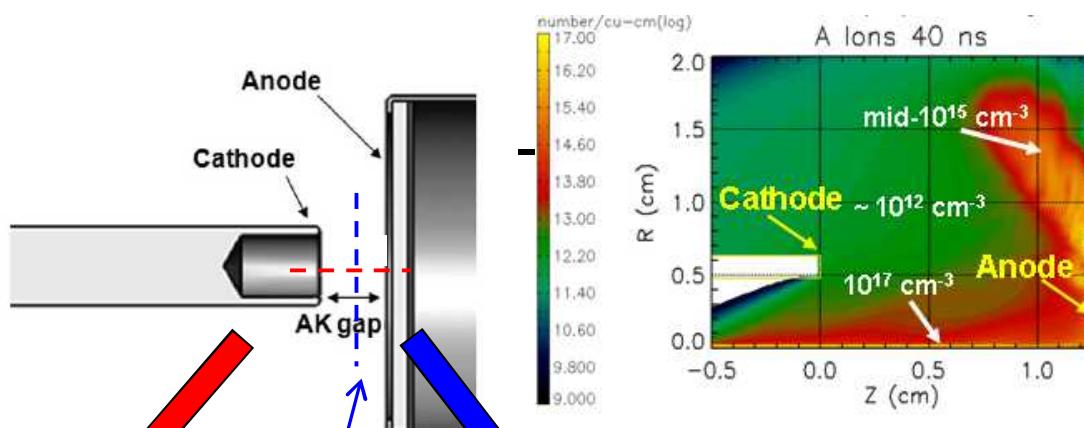
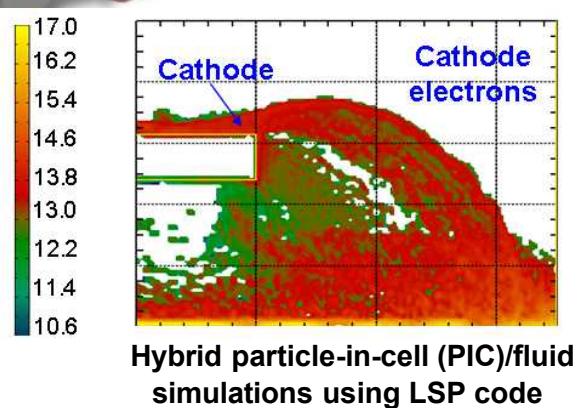
## Princeton Instruments Quad-Ro CCD

- 24  $\mu$ m pixels
- 50mm chip



Princeton Instruments Quad-Ro CCD  
(Streak camera detector)

# Typical Streaked Images of A-K Gap Plasmas

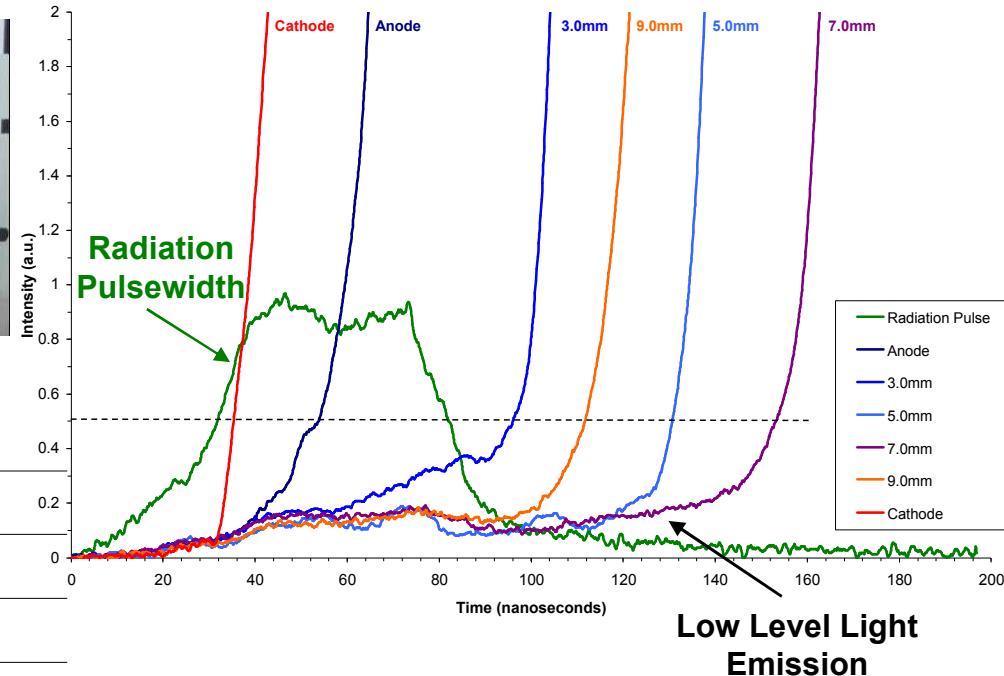
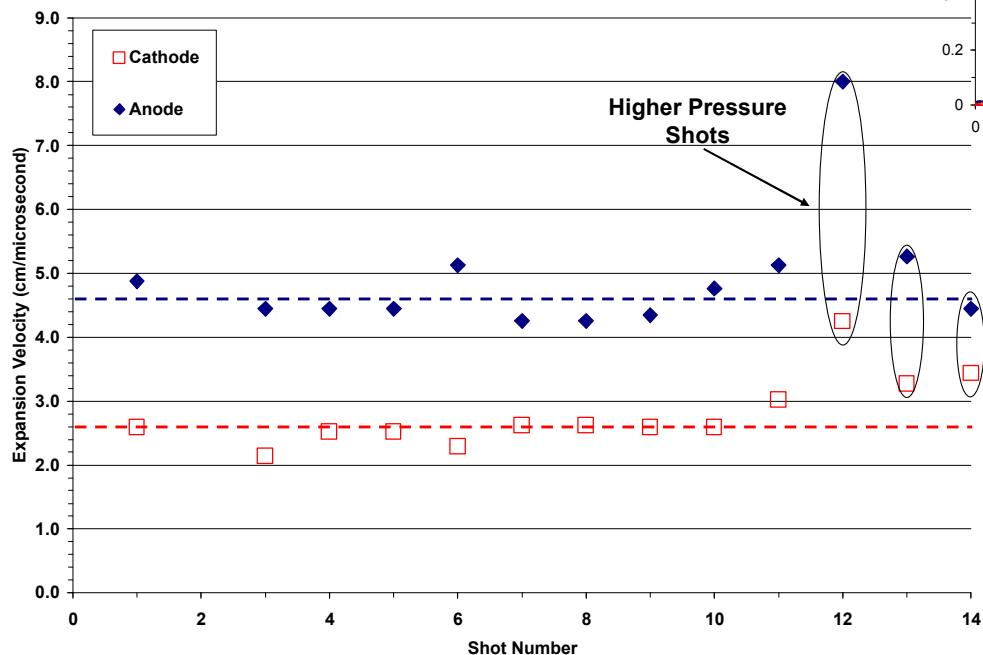


# Plasma Propagation Measurements using Silicon Avalanche Photodetectors

Anode Expansion Velocity: 4.6 +/- 0.3cm/μsec; Cathode Expansion Velocity: 2.6 +/- 0.2cm/μsec



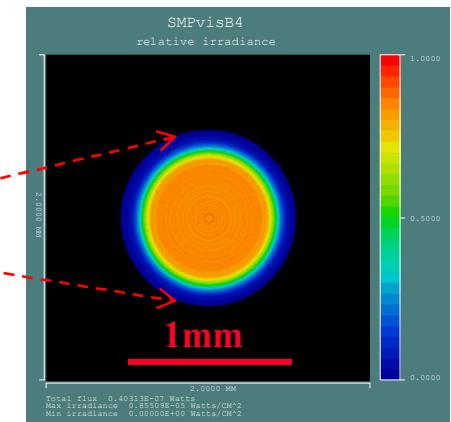
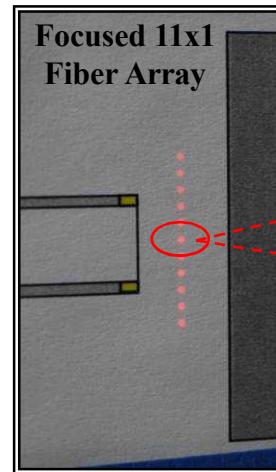
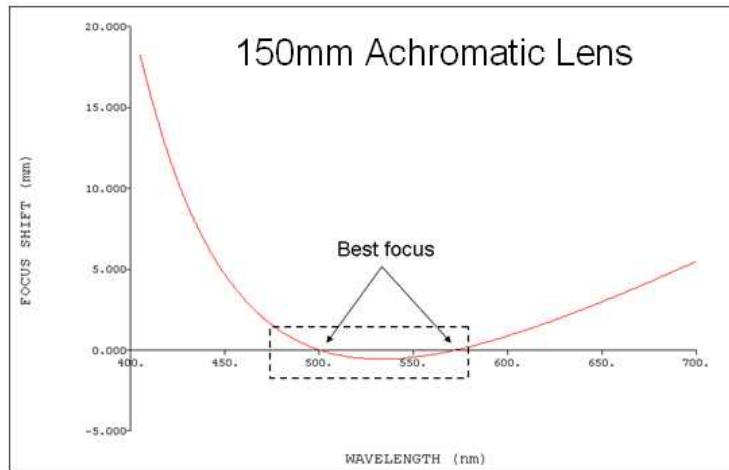
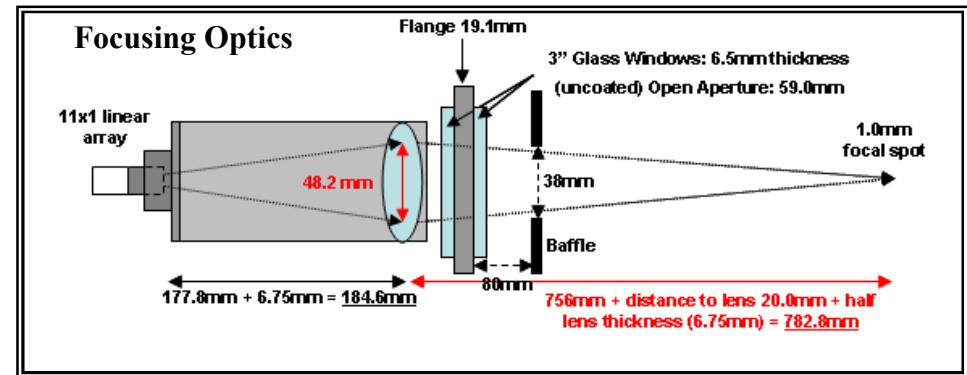
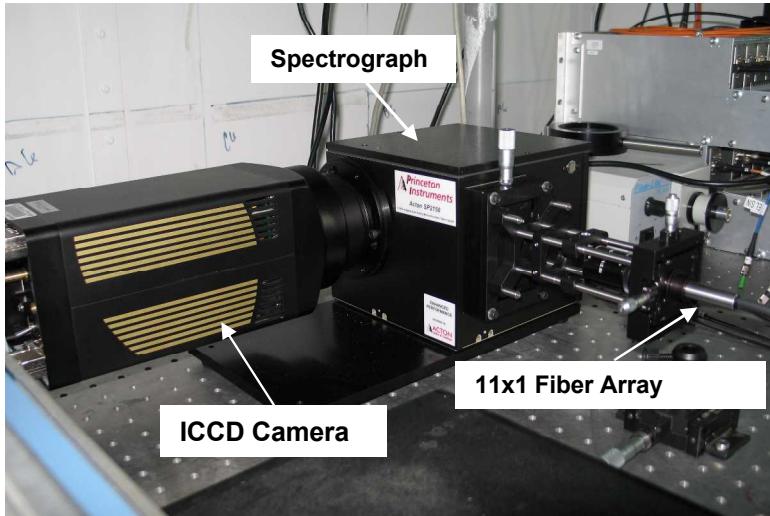
Silicon Avalanche Photodetectors



\*All data taken on the same shot

# Plasma Spectroscopy Diagnostic

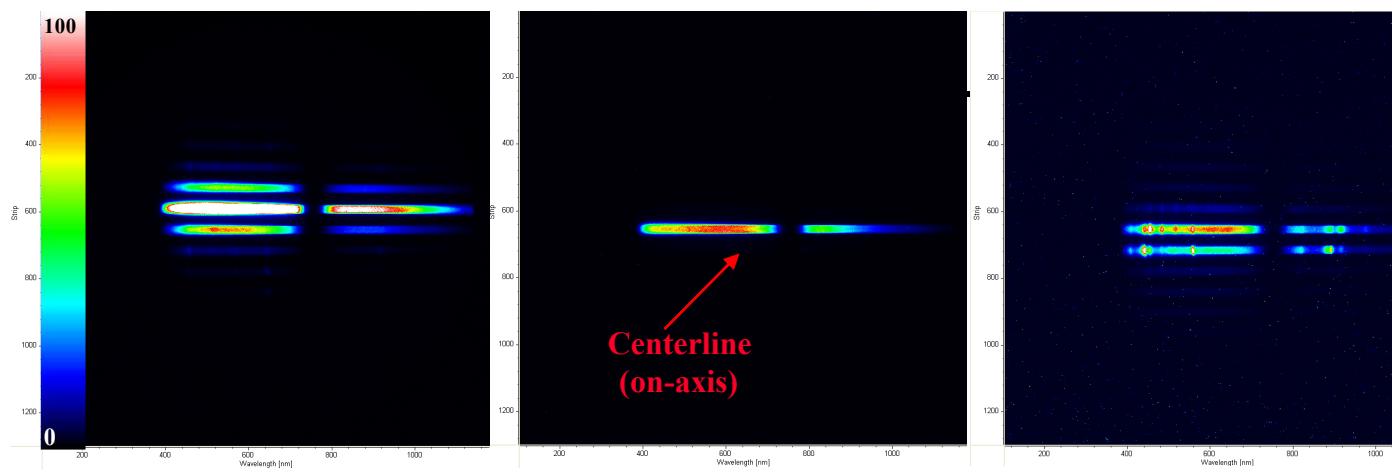
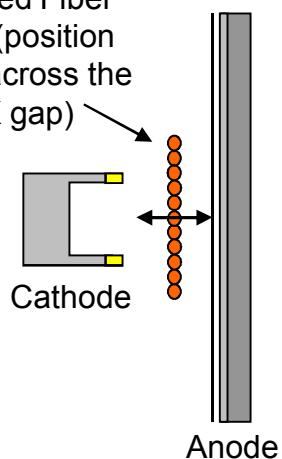
## Spectrograph with ICCD camera



**Fiber Focal Spot Size**

# Radial Distribution of Spectra at Different Axial Locations (spectra collected on separate shots)

Focused Fiber Array (position varied across the A-K gap)



Anode

1/6 Gap

1/3 Gap

Mid-Gap

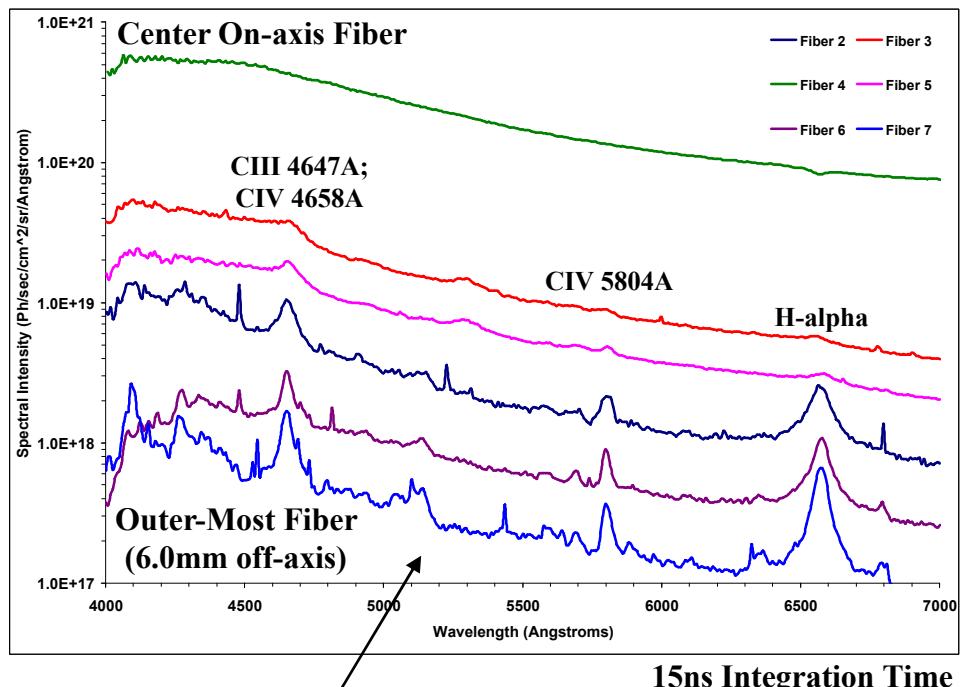
2/3 Gap

5/6 Gap

Cathode

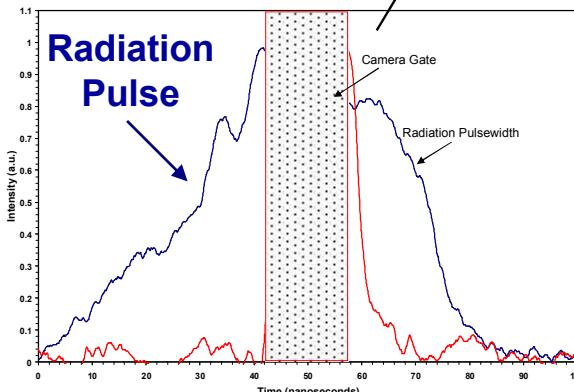
# Spectral Data at Anode Surface During the Radiation Pulse

- Spectra collected along the anode surface during the radiation pulse consist of carbon ion lines, hydrogen neutrals, and continua.
- Line of sight traverses plasmas with different properties.
- Plasma density decreases by a factor of ~35x from the center outward to 6mm.
- Asymmetries in plasma composition and density can be observed across the surface.
- Intensities calibrated in absolute units<sup>3</sup>.



15ns Integration Time

Spectra collected between 42-57ns



## Carbon Ion Lines Observed

- CIII 4647A
- CIV 4658A
- CIV 5804A

\*Red box indicates when in the radiation pulse the spectra was collected.

<sup>3</sup>M.D. Johnston, B.V. Oliver, D.W. Droemer, B. Frogget, et al., *Review of Sci. Instruments*, Vol. 83, No. 8, p. 083108-1.

# Sample Analyses of Spectral Data off the Anode Surface Following the Radiation Pulse

Electron densities are determined from Stark Broadening of the H-alpha line and from absolute continuum intensities using collisional-radiative (CR) spectral analysis. Electron temperatures are obtained from CIII/CIV line ratios.

## Fiber 7 (6.0mm off-axis on the anode surface)

$N_e$  from H-alpha:  $7.4 \times 10^{17} \text{ cm}^{-3}$

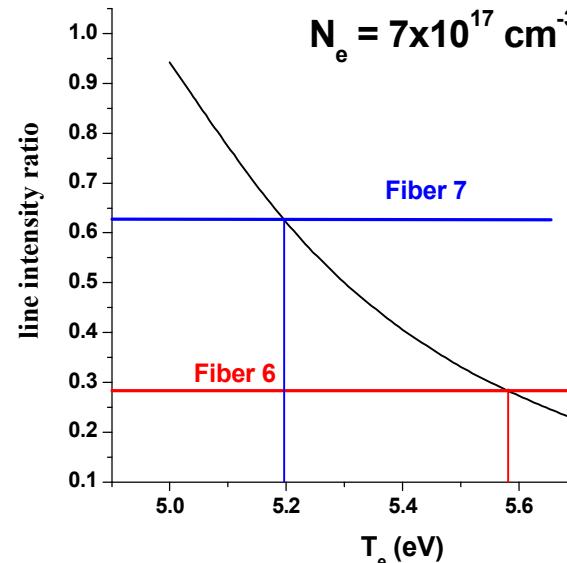
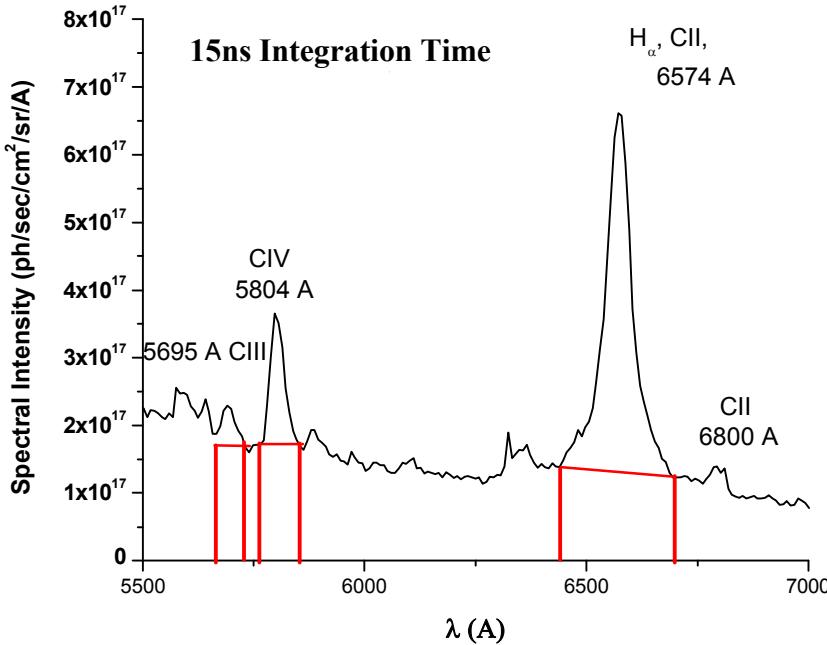
$N_e$  from Continuum:  $2.9 \times 10^{17} \text{ cm}^{-3}$

Electron Temp. ( $T_e$ ): 5.2eV

$N_{\text{hydrogen}} (Z = 1)$ :  $3.2 \times 10^{17} \text{ cm}^{-3}$  (45%)

$N_{\text{carbon}} (Z = 2.9)$ :  $3.0 \times 10^{16} \text{ cm}^{-3}$  (12%)

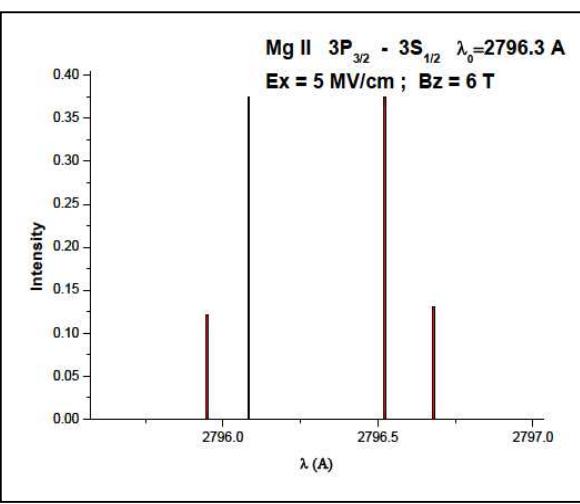
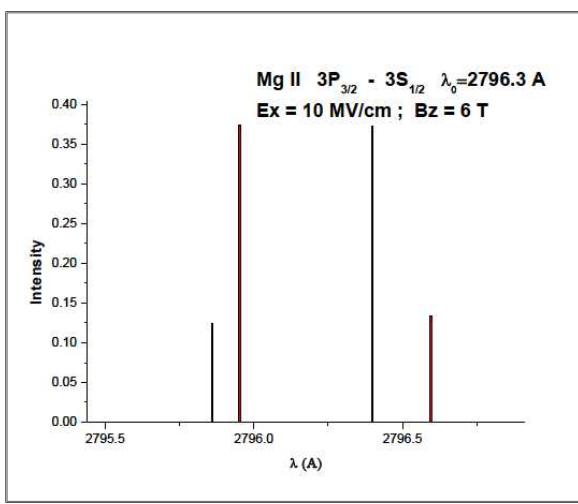
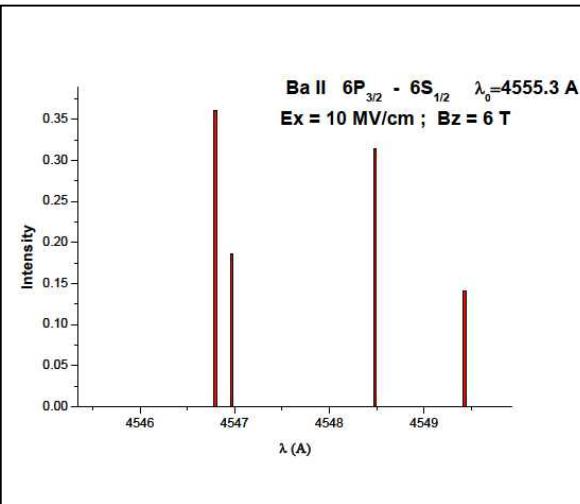
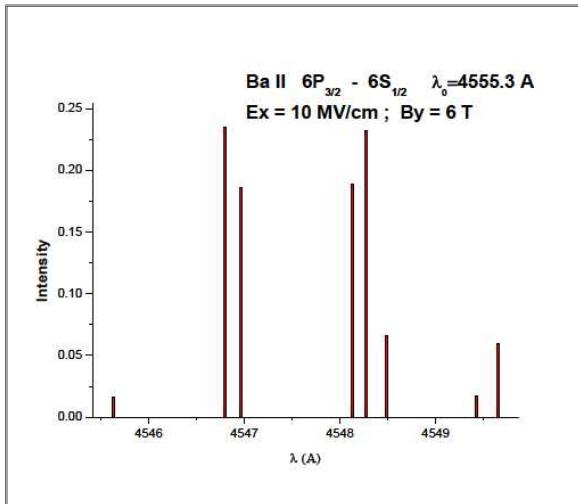
$N_{e(\text{other})}$ :  $3.0 \times 10^{17} \text{ cm}^{-3}$  (43%)



\*Continuum density is averaged over the full fiber viewing area, while Stark broadening is a localized measurement.

\*\*Analyses use the optical streak images to determine pathlengths through the plasma volumes in time.

# Electric and Magnetic Field Measurements in E-Beam Diodes



- Electric and magnetic fields present in e-beam diodes fielded at RITS can be measured spectroscopy.
- Very high electric fields (MV/cm) cause shifts in the transition frequencies of spectral lines (second-order Stark effect). These shifts can be calculated and measured.
- Similarly, strong magnetic fields (several Tesla), cause splitting of spectral lines (Zeeman splitting), which can be calculated and measured.
- Through a judicious choice of transition lines and species, very large E and B fields can be measured in the vacuum gap and within the dense plasma regions.



# Summary

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- Dense plasmas are formed on electrode surfaces in the SMP diode during the ~45ns FWHM radiation pulse. These plasmas migrate into the A-K gap at velocities of 5-10cm/μsec.
- Spectroscopic data shows that these plasmas are composed primarily of hydrogen and carbon ion species. Electron densities of up to  $10^{19}$  cm<sup>-3</sup> have been measured on axis at the anode surface during the x-ray radiation pulse.
- It is believed that these “dense” plasma are responsible for the gradual impedance decay observed during the x-ray radiation pulse. In addition, a “rapid” impedance collapse is observed on some shots, and experiments are planned to look at this phenomena spectroscopically.
- Spectroscopic data is incorporated into LSP, a hybrid particle-in-cell / fluid dynamic code, to help design the next generation of enhanced radiographic sources.
- This type of information (density and temperature profiles in time) enhances our physics understanding of the role of plasmas in e-beam diodes.